# INDIAN INSTITUTE OF SCIENCE EDUCATION AND RESEARCH THIRUVANANTHAPURAM [IISER-TVM]

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Advt. No. IISER/P&S/EOI/10/13

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# NOTICE INVITING EXPRESSION OF INTEREST (EOI)

Separate Expression of Interest (EOI) is invited for following equipments required in Physics Research Labs.

### 1. <u>Electron Beam Lithography System:</u>

This equipment will be used for conducting nanoscale lithography down to 20 nanometer in feature size. It shall be equipped with a thermal field emission electron source having beam energy of 25kV or higher, resolution of a few nanometers, a fast beam blanker and, a laser interferometer controlled specimen stage.

#### 2. Direct Laser Writer

This equipment will be used for making patterns down to one micro-meter in size with a positional accuracy of +/-500 nanometers or better. It shall be equipped with multiple writing modes and optical autofocusing mechanism and shall be capable of performing lithography on an area of 100 mm x 100 mm or larger using g-line, h-line, SU-8 and other generally used photoresists on common semiconductors. Also it shall be capable of performing lithography on direct write glass.

### TERMS & CONDITIONS:

- 1. Separate EOI shall be sent for each item.
- 2. EOI shall contain profile of the company, details of the product and other necessary inputs.
- 3. List of Institutions in India (with contact name and telephone of the end users) where similar equipments are supplied by those who respond to this EOI.
- 4. EOI shall be sent to the OIC (Purchase & Stores), IISERTVM at the above address in sealed cover/packets <u>superscribing</u> <u>Adv.No. IISER/P&S/EOI/10/13, Sl.No. and name of the</u> <u>Equipment and the due date (6<sup>th</sup> January 2014 - 3PM)</u>.
- 5. Shortlisted sources may be invited for a presentation/ discussion at a later date.

REGISTRAR IISERTVM